

JFW

PATENT APPLICATION

In re the Application of

Attn: OIPE

Tatsuo ITO et al.

Application No.: 10/502,389

Docket No.: 120503

Filed: July 26, 2004

For: METHOD FOR MANUFACTURING SEMICONDUCTOR WAFER, METHOD FOR RECEIVING ORDER FOR MANUFACTURE OF SEMICONDUCTOR WAFER, AND SYSTEM FOR RECEIVING ORDER FOR MANUFACTURE OF SEMICONDUCTOR WAFER

REQUEST FOR CORRECTION OF PALM RECORDS

Commissioner for Patents
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Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,


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JAO:EDM/cqc

Date: January 5, 2005

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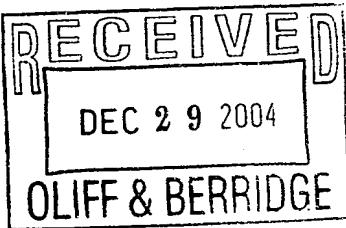
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APPL NO.	FILING OR 371 (C) DATE	ART UNIT	FIL FEE REC'D	ATTY.DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/502,389	07/26/2004	2812	1190	120503	6	35	3

25944
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CONFIRMATION NO. 3456

FILING RECEIPT



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Date Mailed: 12/28/2004

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Domestic Priority data as claimed by applicant

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Foreign Applications

JAPAN 200219334 01/29/2002

Projected Publication Date: 04/07/2005**Non-Publication Request:** No**Early Publication Request:** No

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Title

~~Semiconductor wafer manufacturing method, semiconductor wafer manufacturing order acceptance method, and semiconductor wafer manufacturing order acceptance system~~

Preliminary Class

438

Method for Manufacturing Semiconductor Wafer, Method for Receiving Order for Manufacture of Semiconductor Wafer, and System for Receiving Order for Manufacture of Semiconductor Wafer

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